

**SECTION 2. FORMS PTO/SB/08A and 08B (formerly Form PTO-1449)**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Nunan et al. Attorney Docket: 2550/193  
Serial No: Not yet assigned Art Group Unit: Not yet assigned  
Date Filed: March 2, 2004 Examiner Name: Not yet assigned  
Invention: Single Crystal Silicon Sensor With Additional Layer And Method Of Producing  
The Same

**LIST OF PATENTS AND PUBLICATIONS FOR  
APPLICANT'S INFORMATION DISCLOSURE STATEMENT**

U.S. PATENT DOCUMENTS					
Examiner Initials	Reference Number	Document Number	Issue Date	Inventor	Class/Subclass
BSK	AA	US 5,939,633	08/17/1999	Judy	73/514.32
J	AB	US 6,505,511 B1	01/14/2003	Geen et al.	73/504.12
J	AC	US 5,569,621	10/29/1996	Yallup et al.	437/62
J	AD	US 6,465,280	10/15/2002	Martin et al.	438/125

OTHER DOCUMENTS			
Examiner Initials	Reference Number	Author	Title of Article, Title of Journal, Volume Number, Page Numbers, Date
BSK	AE	P.-C. Hsu et al.	A High Sensitivity Polysilicon Diaphragm Condensor Microphone, 1998 MEMS Conference, Pgs. 1-6, Jan. 25-29, 1998.

Examiner Signature: \_\_\_\_\_

Date Considered: \_\_\_\_\_

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation *if not* in conformance and not considered. Include copy of this form with next communication to applicant.

**SECTION 2. FORMS PTO/SB/08A and 08B (formerly Form PTO-1449)**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: Nunan et al.

Attorney Docket: 2550/193

Serial No: 10/791,638

Art Group Unit: 2812

Date Filed: March 2, 2004 6/22/05

Examiner Name: Not Yet Assigned

Invention: SINGLE CRYSTAL SILICON SENSOR WITH ADDITIONAL LAYER AND METHOD OF PRODUCING THE SAME

**LIST OF PATENTS AND PUBLICATIONS FOR  
APPLICANT'S SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

U.S. PATENT PUBLICATION DOCUMENTS					
Examiner Initials	Reference Number	Document Number	Publication Date	Inventor	Class/Subclass
JS/KS	AF	US 2002/127760	Sept. 12, 2002	Yeh et al.	438/50

FOREIGN PATENT DOCUMENTS						
Examiner Initials	Reference Number	Country Code	Document Number	Publication Date	Patentee or Applicant	Class/Subclass
JS/KS	AG	WO	99/00155	Jan. 7, 1999	Lebouitz et al.	A61M 5/32
JS/KS	AH	EP	1325885	July 9, 2003	Xerox Corporation	B81B 3/00
JS/KS	AI	WO	00/42231	July 20, 2000	Franke et al.	C23C

OTHER DOCUMENTS			
Examiner Initials	Reference Number	Author	Title of Article, Title of Journal, Volume Number, Page Numbers, Date
JS/KS	AJ	Yi et al.	<i>A Micro Active Probe Device Compatible with SOI-CMOS Technologies</i> , Journal of Microelectromechanical Systems, IEEE Inc., Vol. 6, No. 3, September 1987, 7 pages.
JS/KS	AK	Calamita, et al.	<i>Hybrid integration of light emitters and detectors with SOI based Micro-Opto-Electro-Mechanical Systems (MOEMS)</i> , Proceedings of the SPIE, Silicon-Based and Hybrid Optoelectronics III, 23-24 Jan. 2001, Vol. 4293, 2001, pages 32-45.
JS/KS	AL	Franke et al.	<i>Post-CMOS Integration of Germanium Microstructures</i> , Micro Electro Mechanical Systems, 1999, MEMS '99, Twelfth IEEE International Conference, 17-21 Jan., 1999, pages 630-637.
JS/KS	AM	Authorized Officer Katrin Sommermeyer	<i>Invitation to Pay Additional Fees/ Communication Relating to the Results of the Partial International Search</i> , International Searching Authority, March 30, 2005, 6 pages.

*JS/KS* 12/10/05